**Docket #:** S11-473A

# Printing Lens

Stanford researchers have developed a method for manufacturing a UV curable epoxy micro lens. Apertures of arbitrary size can be manufactured for micro lenses using this method. This micro lens is particularly useful in microscopes having a shorter optical path length over conventional optical microscopes.

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**Prakash et al.**

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(54) **OPTICAL LENS FABRICATION**

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( * ) Notice: Subject to any disclaimer, the term of this patent is extended or adjusted under 35 U.S.C. 154(b) by 154 days.

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***G02B 3/00*** (2006.01)
***G02B 9/00*** (2006.01)
(Continued)

(52) **U.S. Cl.**
CPC ..... ***G02B 21/02*** (2013.01); ***B29D 11/00365*** (2013.01); ***B29D 11/00432*** (2013.01);
(Continued)

(58) **Field of Classification Search**
CPC ..... G02B 21/02; G02B 3/0087; G02B 5/005; G02B 21/0008; G02B 3/00; B29D 11/00432; B29D 11/00365
See application file for complete search history.

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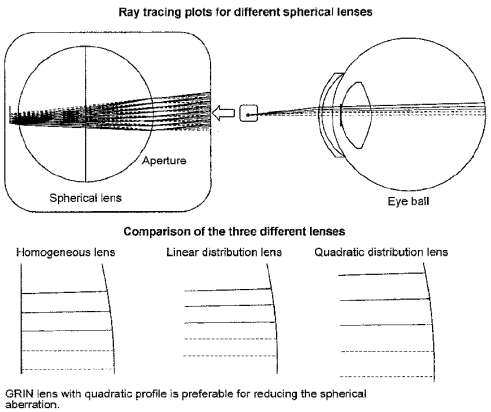
(57) **ABSTRACT**

Optical lenses and methods for manufacturing optical lenses are disclosed herein. Lenses having a reduced aperture size are also disclosed herein along with methods for making the same. The optical lenses disclosed herein can be made having improved optical properties. The lenses can be used in optical microscopes, including optical microscopes with a shorter optical path relative to conventional optical microscopes.

**20 Claims, 17 Drawing Sheets**



## Patents

- Published Application: WO2014022652
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